

# INFORMATION DISCLOSURE CITATION

(Use several sheets if necessary)

Docket Number (Optional)  
YPL-0026

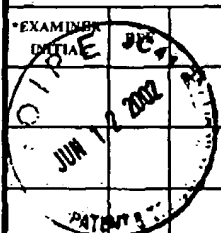
Application Number  
10/086,496

Applicant(s)  
GEUN-YOUNG YEOM, ET AL.

Filing Date  
February 28, 2002

Group Art Unit

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
						

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## FOREIGN PATENT DOCUMENTS

REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO

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## OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

<p>ame</p>	<p>D.B. Oaks, W.G. Lawrence and A.H. Gelb, "Selective, Anisotropic and Damage-Free SiO<sub>2</sub> Etching with a Hyperthermal Atomic Beam", Physical Sciences Inc., 20 New England Business Center, Andover, MA 01810, 7 pages</p>
<p>ame</p>	<p>M.J. Goeckner, T.K. Bennett, Jaeyoung Park, Z. Wang and S.A. Cohen, "Reduction of Residual Charge in Surface-Neutralization-Based Neutral Beams", 1997 2nd Int'l Symposium on Plasma Process-Induced Damage; May 13-14, pages 175-178</p>

EXAMINER  
C. J. Nichols Lowell

DATE CONSIDERED  
03-10-04

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B.A. Helmer and D.B. Graves "Molecular dynamics simulations of Cl<sub>2</sub> impacts onto a chlorinated silicon surface: Energies and angles of the reflected Cl<sub>2</sub> and Cl fragments", J.Vac. Sci. Technol. A 17(5), Sep/Oct 1999, pages 2759 -2770

Takashi Yunogami, Ken'etsu Yokogawa, and Tatsumi Mizutani, "Development of neutral-beam-assisted etcher", J.Vac. Sci. Technol. A 13(3), May/June 1995, pages 952 - 958

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*A. Mitchell Gowell*

DATE CONSIDERED

*03-10-04*

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